



Metrics NA TC Chapter

NA Fall 2019 Meetings

Wednesday, November 6

SEMI HQ, Milpitas, California

15:00 – 18:00

AGENDA

	Time
1 Welcome/Call to Order	15:00-15:15
1.1 Introductions	
1.2 Required Meeting Elements (Membership Requirements, Antitrust and Intellectual Property Reminders, and Effective Meeting Guidelines)	
1.3 Agenda Review	
2 Review of Previous Meeting Minutes (including open Action Items review)	15:15-15:20
3 Staff Report	15:20-15:25
4 Liaison Reports	15:25-15:35
4.1 Japan TC Chapter	
4.2 Technical Editors Board – David Bouldin	
4.3 ESDA Liaison Report – Russell Fitzpatrick	
5 Ballot Review (including Safety and IP Checks)	15:35-16:15

#	When	SC/TF/WG	Details
R6472	Cycle 6 2019	CCC TM TF	New Standard: <i>Test Method for Measuring Surface Metal Contamination Through ICP-MS of Critical Chamber Components Used in Semiconductor Wafer Processing</i>
6569	Cycle 6 2019	n/a	Reapproval to SEMI E165-0813: <i>Guide for a Comprehensive Equipment Training System When Dedicated Training Equipment is not Available</i>
6568	Cycle 6 2019	n/a	Reapproval to SEMI E150-0314: <i>Guide for Equipment Training Best Practices</i>
6567	Cycle 6 2019	n/a	Reapproval to SEMI E149-0314: <i>Guide for Equipment Supplier-Provided Documentation for the Acquisition and Use of Manufacturing Equipment</i>



6 Break (optional)	16:15-16:25
7 Subcommittee & Task Force Reports (including leadership and TF changes)	16:25-16:50
7.1 Critical Chamber Components (CCC) Test Methods Task Force	
7.2 Equipment RAMP Metrics Task Force	
7.3 ESD/ESC Task Force	
7.4 RF Measurements (RFM) Task Force <tentative>	
7.5 EMC Task Force <tentative>	
8 Old Business	16:50-17:10
8.1 Standards due for Five-Year Review	
8.2 SNARFs approaching Three-Year Document Development Project Period	
9 New Business	17:10-17:45
9.1 New TFOF(s) and SNARF(s)	
9.2 Ballot Authorizations	
9.3 Upcoming Ballot(s)	
10 New Action Item Review	17:45-17:55
11 Next Meeting – Spring 2020 Standards Meetings, Milpitas, CA	17:55-18:00
11.1 Tuesday, March 31, 2020 (Tentative)	
• EMC TF (11:00 – 12:00)	
• ESD/ESC TF (13:00 – 14:30)	
• Critical Chamber Components (CCC) Test Methods TF (14:30 – 16:30)	
11.2 Wednesday, April 1, 2020 (Tentative)	
• Equipment RAMP Metrics TF (9:00 – 11:00)	
• RF Measurements TF (12:30-14:30)	
• Metrics NA TC Chapter (15:00 – 18:00)	
12 Adjournment	18:00

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